

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

<b>APPLICANT:</b>	<b>Masaki Shioya</b>	<b>GROUP: 2121</b>
<b>SERIAL NO:</b>	<b>10/822,266</b>	<b>EXAMINER: R. Hartman, Jr.</b>
<b>FILED:</b>	<b>April 8, 2004</b>	<b>CONFIRMATION: 2711</b>
<b>FOR:</b>	<b>FACILITY CONTROL MONITOR METHOD AND FACILITY CONTROL MONITOR APPARATUS</b>	

Commissioner for Patents  
PO Box 1450  
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**RESPONSE UNDER 37 C.F.R. 1.116**

In response to the Office Action mailed February 21, 2007, the following amendments and remarks are respectfully submitted in connection with the above-identified application.